

# **MPI TS150 | 150 mm Manual Probe System**

## **For accurate and reliable DC/CV and RF measurements**

### **Microscope Mount and Movement**

- Stable bridge for high quality optics
- Linear Z lift for easy reconfiguration
- 25 x 25 mm air bearing or 50 x 50 mm linear XY movement

### **Adjustable Platen Height**

- Micrometer control for precise adjustment
- 20 mm range for various applications

### **Probe Platen**

- Stable and rigid design
- Supports DC/CV and RF measurements
- Rectangular adjustments for RF positioners
- Designed for maximum thermal stability

### **RF Calibration**

- 2 auxiliary chucks for calibration substrates
- Built-in ceramic for accurate calibration
- 1 µm flatness for consistent contact quality

### **Thermal Chuck Integration**

- Seamless integration of the thermal controller touch screen panel provides most convenient operation

### **Unique Platen Lift w/ Probe Hover Control™**

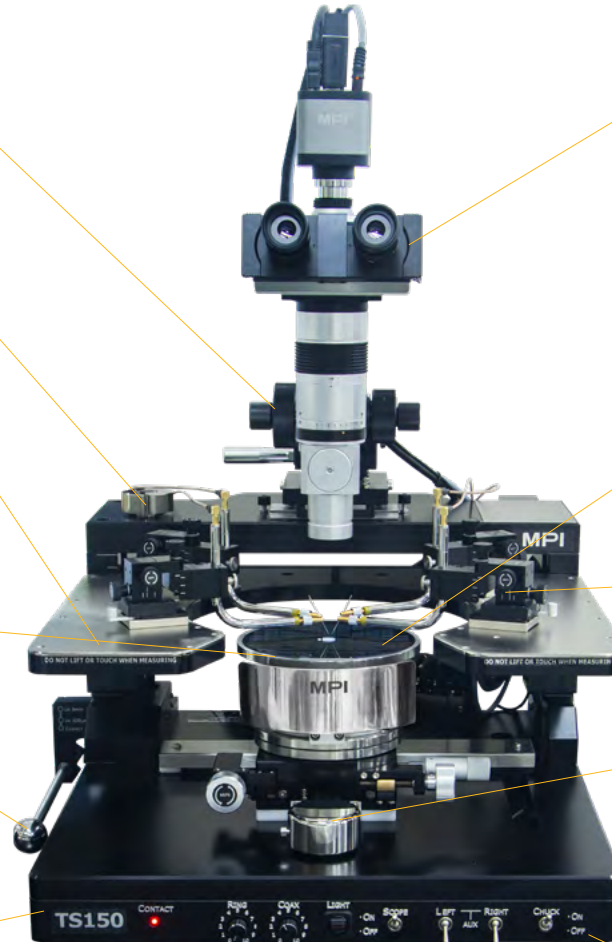
- Three discrete positions - contact, separation (300 µm), safety loading (3 mm) and additional stop at alignment height at 50, 100 or 150 µm
- Safety lock function at loading position
- "Auto Contact" position with ±1 µm repeatability for consistent contact quality

### **Ultra Small Footprint**

- Designed for bench top use
- Comes with vibration absorber base
- Low profile design for maximum usability
- Ideal for load pull applications

### **\*\*\*Available Options\*\*\***

- Vibration isolation platform
- EMI-shielded DarkBox
- Vacuum pump and air compressor unit
- Table with integrated rack for thermal controller, computer and keyboard push tray - Dual monitor stand option & Instrument shelf option



### **Microscope and Optics Options**

- Various optical configurations available for different application needs
- Stereo microscope MPI ST45 or single tube with eyepieces MPI SZ10
- Single tube microscopes EZ10 and MZ12 with up to 12x zoom, 101 mm working distance and down to 1.68 µm resolution
- Modular high-performance microscopes Mitutoyo FS70 and Motic PSM-1000
- HDMI cameras with monitor-based user interface - no computer required

### **Modular Chucks**

- Various non-thermal or thermal chucks
- Choice of triaxial or coaxial connection
- Wide range of temperature up to 300 °C
- Field upgradable for reduced cost of ownership
- Easy switch between center & small wafer size control

### **DC and RF Positioners**

- Supports up to 4 RF and 10 DC positioners
- Wide range of positioners available
- Dedicated probe arms for for coaxial, triaxial, Kelvin and RF measurements

### **Chuck XY-Theta Stage Movement**

- Unique puck controlled air bearing stage for quick single-handed operation
- 180 x 230 mm XY total stage movement
- Including 25 x 25 mm fine micrometer control
- Resolution < 1.0 µm (0.04 mils) @ 500 µm/rev
- Extra wide Y-range for easy loading
- ±5° Theta fine adjustment
- Micrometer control for precise adjustment

### **Front Mounted Vacuum Control**

- Easy access
- Clearly marked